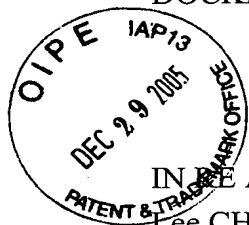


DOCKET NO.: 255873US6YAPCT/phh

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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

IN RE APPLICATION OF:

Lee CHEN

SERIAL NO: 10/501,987

GROUP: 1763

FILED: June 6, 2005

EXAMINER: Allan W. OLSEN

FOR: PLASMA ETCHING OF NI-CONTAINING MATERIALS

**LETTER**

Mail Stop DD  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Submitted herewith is an International Written Opinion for the Examiner's consideration. The reference(s) cited therein have been previously filed with the International Search Report in an Information Disclosure Statement submitted to the U.S. Patent and Trademark Office on July 21, 2004.

Respectfully Submitted,

OBLON, SPIVAK, McCLELLAND,  
MAIER & NEUSTADT, P.C.

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Steven P. Weihrouch  
Registration No. 32,829

Customer Number

**22850**

Tel. (703) 413-3000  
Fax. (703) 413-2220  
(OSMMN 10/05)

Edwin D. Garlepp

Registration No. 45,330

Corwin P. Umbach, Ph.D.  
Registration No. 40,211